

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	593	(substrate same conduct\$5 near3 (beam rod bar shaft)).clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/03/09 08:05
L2	300	1 and conduct\$5 near3 (pad layer coating film thin).clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/03/09 08:06
L3	10	2 and cantilever.clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/03/09 08:18
L4	49	2 and cantilever	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/03/09 08:18
L5	31	4 and (micromechanical MEMS)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/03/09 08:19
L6	0	4 and (resistan\$5 near3 (test\$5 detect\$5 sens\$5 estimat\$5 evalut\$5 determin\$5 measur\$5 transducer cell meter gauge monitor\$5)).clm.	USPAT; EPO; JPO	OR	ON	2005/03/09 08:23
L7	2	2 and (resistan\$5 near3 (test\$5 detect\$5 sens\$5 estimat\$5 evalut\$5 determin\$5 measur\$5 transducer cell meter gauge monitor\$5)).clm.	USPAT; EPO; JPO	OR	ON	2005/03/09 08:24